



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:)
Wen-Ben CHOU et al.) Docket No. LAM2P295
Application No. 09/998,858) Examiner: Chen, Kin Chan
Filed: October 31, 2001) Group Art Unit: 1765
For: METHOD AND APPARATUS FOR) Date: April 24, 2003
NITRIDE SPACER ETCH PROCESS)
IMPLEMENTING *IN SITU* INTERFER-)
OMETRY ENDPOINT DETECTION)
AND NON-INTERFEROMETRY)
ENDPOINT MONITORING)

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, DC 20231 on April 24, 2003.

Signed: 

Diane Schwanbeck

ELECTION OF CLAIMS FOR PROSECUTION ON THE MERITS

Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

In response to the Restriction Requirement dated March 27, 2003, Applicants hereby elect, without traverse, **claims 1-16** (the Group I claims) for prosecution on the merits.

Applicants respectfully request examination on the merits for the subject application. Applicants believe that no fees are required in the filing of this Response; however, if any fees are due to effect consideration of this paper, then the Commissioner is authorized to charge such fees to Deposit Account No. 50-0805 (Order No. LAM2P295).

Respectfully submitted,
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